

**FAX**

Date September 15, 2003

To Examiner Kin Chan Chen

Of PTO Group Art Unit 1765

Fax (703) 872-9311

From Keiko K. Takagi

Subject Amendment filed on August 14, 2003

Our Ref Q61045 Appln No 09/672,776

Conf No 2256 Inventors Fumiyoshi ONO

Pages 8 (including cover sheet)

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#### CERTIFICATION OF FACSIMILE TRANSMISSION

Sir:

I hereby certify that the above identified correspondence is being facsimile transmitted to Examiner Kin Chan Chen at the Patent and Trademark Office on September 15, 2003 at (703) 872-9311.

Respectfully submitted,

*Shannon Shenton*  
Shannon Shenton

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In re application of

Fumiyoshi ONO

Appl. No.: 09/672,776

Group Art Unit: 1765

Confirmation No.: 2256

Examiner: Kin Chan Chen

Filed: September 29, 2000

For: COMPOSITION FOR POLISHING METAL ON SEMICONDUCTOR WAFER AND  
METHOD OF USING SAME

PAPER FILED ENTITLED:

1. Amendment Under 37 C.F.R. §1.116 (6 pages)

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WASHINGTON OFFICE

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DOCKET NO.: Q61045  
ATTORNEY/SEC: BEK/KKT  
Date Filed: August 14, 2003



AMENDMENT UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE  
GROUP 1765  
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q61045

Fumiyoshi ONO

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METHOD OF USING SAME

AMENDMENT UNDER 37 C.F.R. § 1.116

MAIL STOP AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**FILED**  
AUG 14 2003

Sir:

This Amendment is submitted in response to the Office Action dated May 15, 2003, in which the Examiner set a three-month period for response.

Review and reconsideration on the merits in view of the following remarks and amendment is respectfully requested.

Please amend the above-identified application as follows on the accompanying pages.